

F. Silicon and Group-IV Devices and Integration Technology 분과

2017년 2월 14일 (화), 08:30-10:00
Room E (루비, 2층)

[TE1-F] Advanced CMOS Devices I

좌장: 김소영(성균관대학교), 이내인(삼성전자)

TE1-F-1 08:30-08:45	Super Steep Switching FinFET Technology for Ultra-Low Power Operation Eunah Ko and Changhwan Shin <i>Department of Electrical and Computer Engineering, University of Seoul</i>
TE1-F-2 08:45-09:00	Approach for Advancement of Transistor: Vertically Integrated Gate-All-Around Junctionless Nanowire FET Byung-Hyun Lee and Yang-Kyu Choi <i>School of Electrical Engineering, KAIST</i>
TE1-F-3 09:00-09:15	Hump Effects of Triple-Gate Tunnel FETs Encapsulated with an Epitaxial Layer (EL TFETs) Jang Woo Lee and Woo Young Choi <i>¹Department of Electronic Engineering, Sogang University, ²Flash Device Technology Team, SK Hynix Inc.</i>
TE1-F-4 09:15-09:30	Fully Formed, Releasable Single-Crystal Silicon-Metal Oxide Field Effect Transistors based on (100) Silicon Bulk Wafer Kyu-Bong Choi, Byung-Gook Park, and Jong-Ho Lee <i>Department of ECE and ISRC, Seoul National University</i>
TE1-F-5 09:30-09:45	Vertical Gate-All-Around Transistor with Wrapped Contact and Vertically-Stacked Dual Metal Gate for High Current Memory Applications Dongyeon Oh, Junkyo Suh, Kangsik Choi, Sangyong Kim, Seong-Dong Kim, Seokkiu Lee, and Sungjoo Hong <i>R&D Division, SK Hynix Inc.</i>
TE1-F-6 09:45-10:00	Improved Characteristics and V_{TH} Modulation of FD-SOI Tunnel Field Effect Transistor (TFET) Using ALD $HfAlO_x$ and TiN Gate Stack Donghwan Lim, Jae Ho Lee, Myeong Gyoon Chae, Hoon Hee Han, Yu-Rim Jeon, Andrey Sokolov Sergeevich, and Changhwan Choi <i>Division of Materials Science and Engineering, Hanyang University</i>